

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Keisuke KAWAMURA, et al.

SERIAL NO: 10/519,475

GAU: 1792

FILED: December 28, 2004

EXAMINER: Arancibia, M. G.

FOR: APPARATUS FOR PLASMA PROCESSING, METHOD OF PROCESSING SUBSTRATE
THEREWITH, APPARATUS FOR PLASMA-ENHANCED CHEMICAL VAPOR DEPOSITION, AND
METHOD FOR FILM FORMATION THEREWITH

**REQUEST FOR EXTENSION OF TIME
UNDER 37 C.F.R. 1.136**

COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313

SIR:

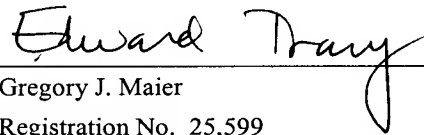
It is hereby requested that a 2nd one-month extension of time be granted to June 29, 2008 for

- ☐ filing a response to the Official Action dated:
- ☐ responding to the requirements in the Notice of Allowability dated:
- ☐ filing the Formal Drawings. The Issue Fee due has been timely filed.
- ☐ responding to the Notice to File Missing Parts of Application dated:
- ☒ filing an RCE. A timely response to the final rejection, due April 29, 2008 has been filed.
- ☐ filing an Appeal Brief. A Notice of Appeal was filed on:
- ☐ Applicant claims small entity status. See 37 CFR 1.27. Therefore, the fee amount shown below is reduced by one-half.

The required fee of \$340.00 is being made by credit card payment and any further charges may be made against the Attorney of Record's Deposit Account No. 15-0030.

Respectfully Submitted,

OBLON, SPIVAK, McCLELLAND,
MAIER & NEUSTADT, P.C.



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